

# IEEE SW Test Workshop

Semiconductor Wafer Test Workshop

June 6 to 9, 2010

San Diego, CA



## Wafer Level ESD Probe Card Solutions



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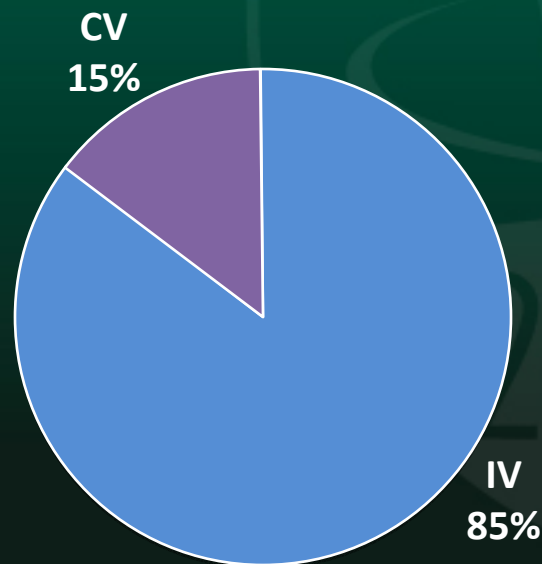
# Agenda

- Review of advances in ESD waveforms required for wafer-level scribeline test
- Challenges related to full TEG pattern automation of ESD test structures
- Solutions for combining full DC and ESD parametric testing in a single touchdown
- Conclusions

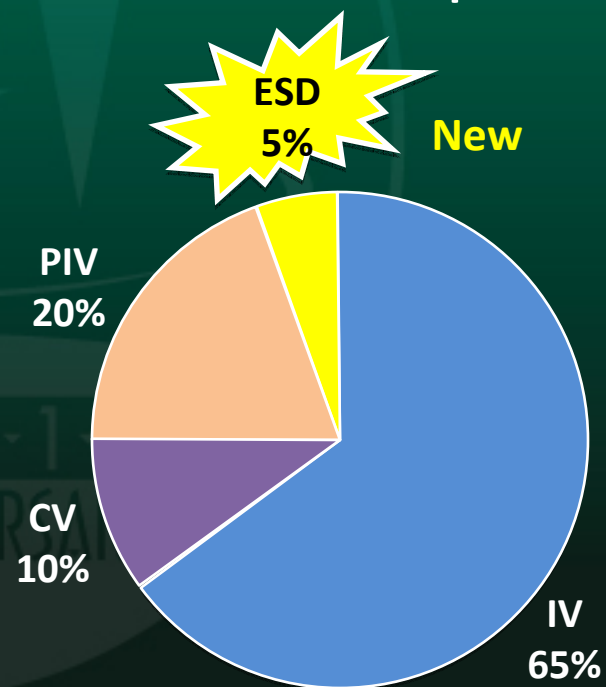


# Evolving Parametric Test Probing

**1990's Traditional DC Para**  
10 MHz Matrix Required



**2010's Expanding to HF Para**  
1 GHz Matrix Required



# ESD Scribeline Tests

- Similar to HF-PIV for power transistor characterization

Type	Device	Freq	Matrix	Test Name
IV	Transistor	1 MHz	10 MHz	Vt, Gm, Vsat, BV, IDVD, IDVG, Gate & Drain Leakage, V-ramp, J-ramp, TDDDB, HCI, Charge Pump, EM
CV	Transistor Oxide	1 MHz	10 MHz	Thick Gate Tox, Field Tox, Diffusion Profiles, Trapped Charge, Mobile Ion, C-gate, C-drain
HF-CV	Transistor Oxide	100 MHz	1 GHz	Thin Gate Tox, Carrier Life Time, Contamination
HF-PIV	Power Transistor	200 MHz	1 GHz	Vt, Gm, Vsat, IDVD, IDVG, Gate Charge, Trapped Charge, CMOS Latch-up (I/O Structure)
ESD	ESD structure	200 MHz	1 GHz	TLP, HBM, MM, HMM (IEC 61000-4-2), WCDM, TDB(time dependent breakdown) , Leakage curves
Flash R-ram	Transistor Resistor	200 MHz	1 GHz	State 0-State 1 Programming Current/Time, Read Leakage Current



# ESD Waveforms

- **TLP – Transmission Line Pulse**
- **HBM – Human Body Model**
- **CDM – Charge Device Model**
- **WCDM – Wafer Charged Device Model**
- **MM – Machine Model**
- **HMM – Human Metal Model (IEC 61000-4-2)**



# TLP & VFTLP Waveforms

- **TLP - Transmission Line Pulse**

- Used for characterization of a ESD structure to a constant voltage pulse
- Not used for simulating ESD events
- Pulse delivery can be by a probe card

10mA -10A  
into 50Ω  
100nS wide

- **VFTLP – Very Fast Transmission Line Pulse**

- Can characterize ESD structures designed for fastest (CDM) protection
- Pulse delivery by manual RF probes

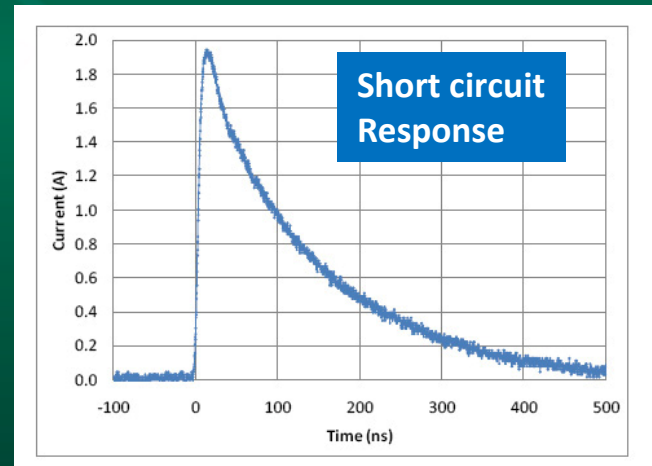
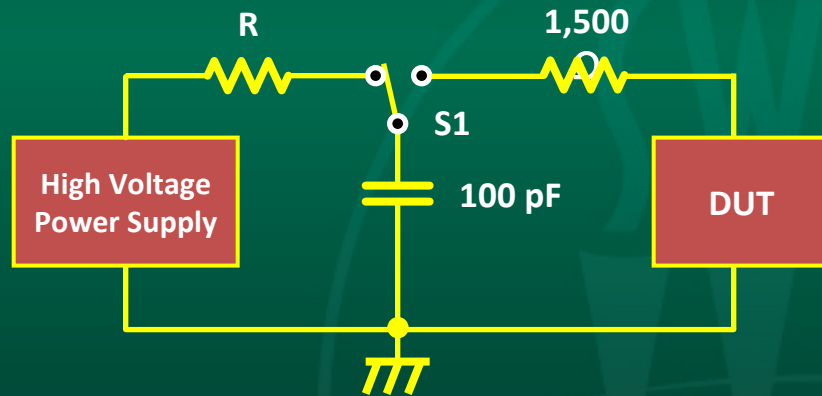
10mA -20A  
into 50Ω  
1-10nS wide



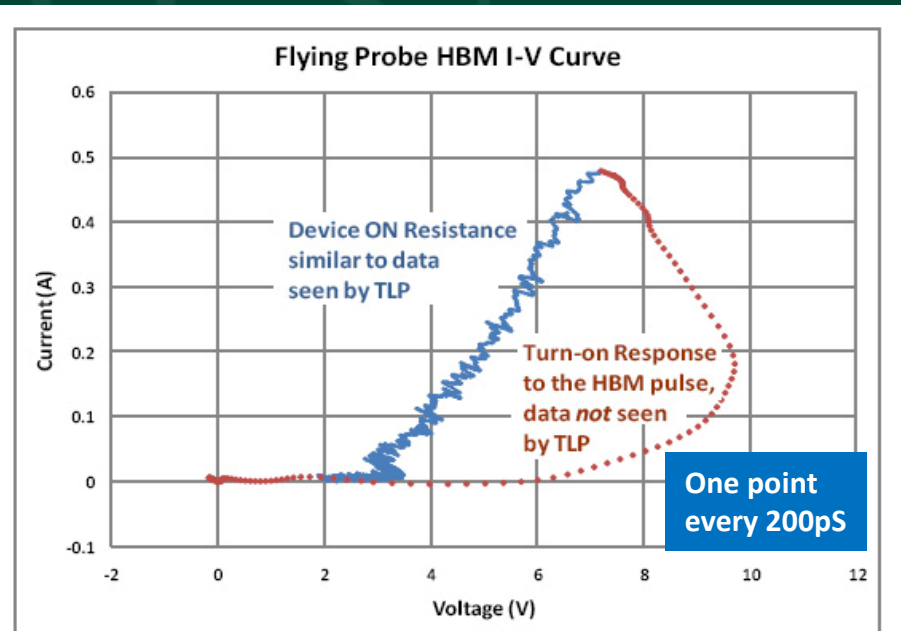
Barth VFTLP System



# HBM (Human Body Model)



- Created by an RC discharge
- Clean PIV waveforms showing turn-on response are possible at the wafer level
  - *Not* seen by TLP
  - *Not* seen at package level

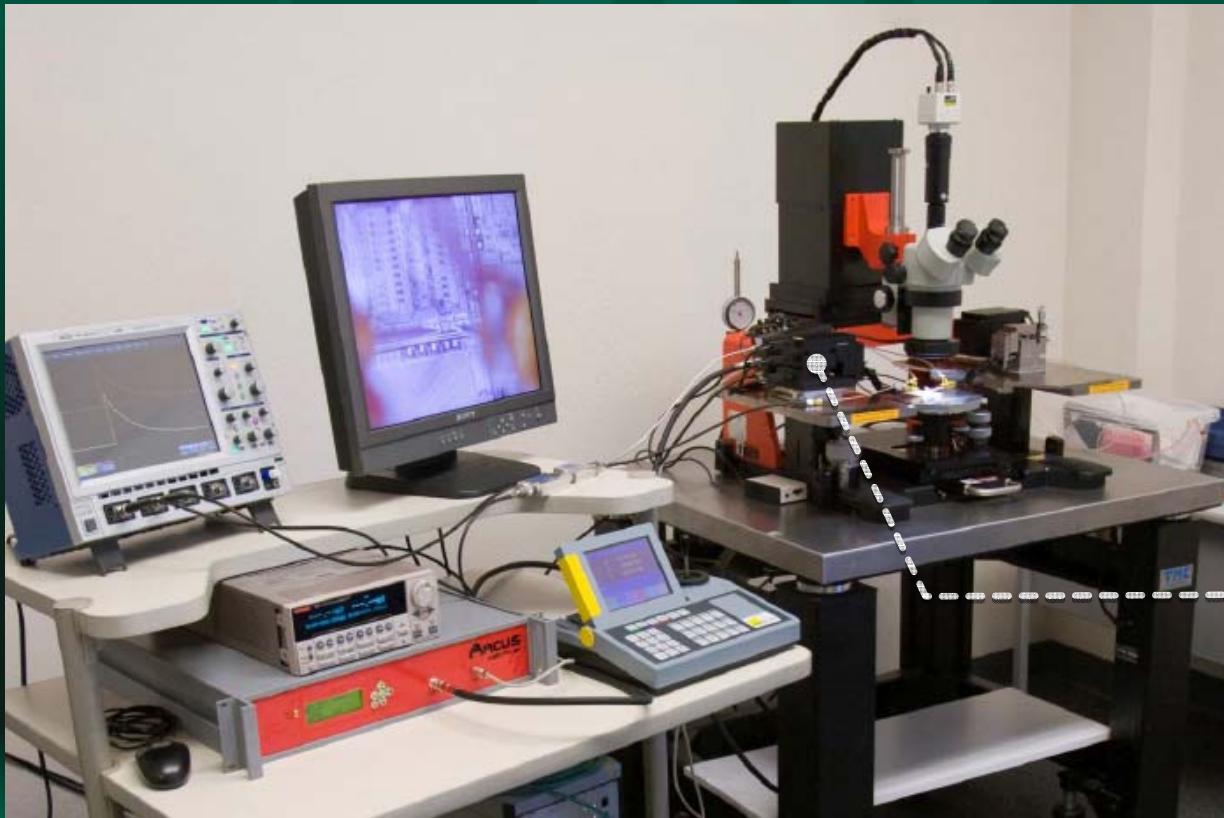


Example of an I-V Curve from a single HBM pulse



# HBM Flying Probe Test System

- ESD testing on wafers, bare die, and packaged parts
- Eliminate parasitic distortions in relay-base test systems
- TLP-like measurements of actual DUT pin response



TDR pod for sensing pulse response at the DUT pads



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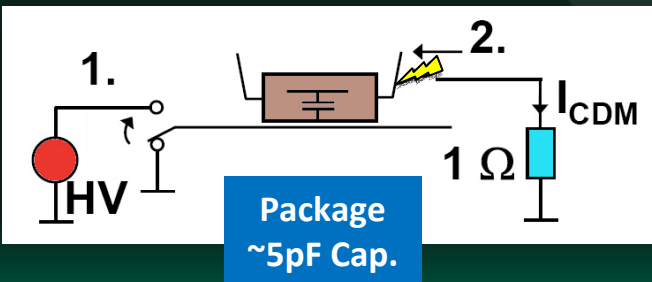
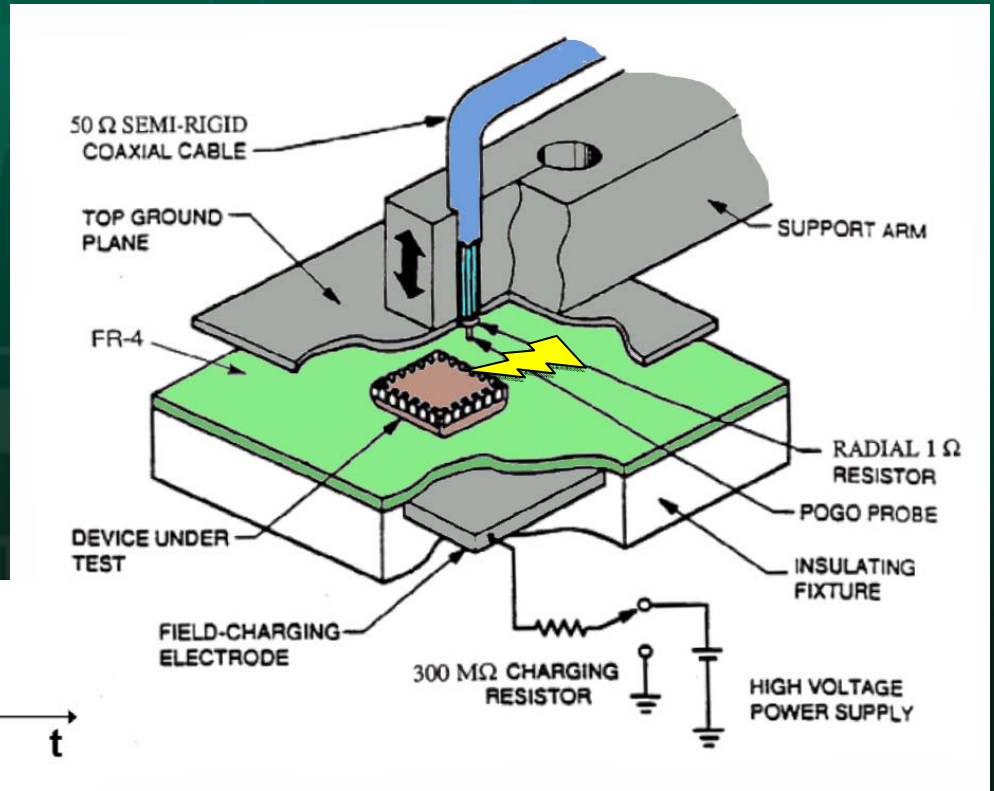
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8



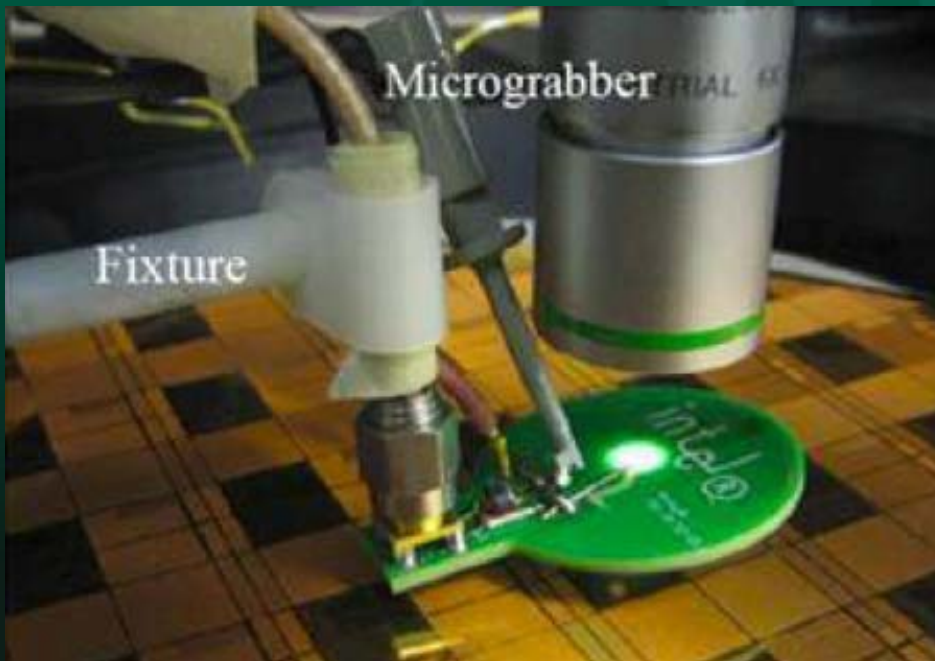
# CDM (Charge Device Model)

- Top ground plane is lowered until pogo pin contact DUT pin
- Discharge path is from charged DUT to grounded pogo pin

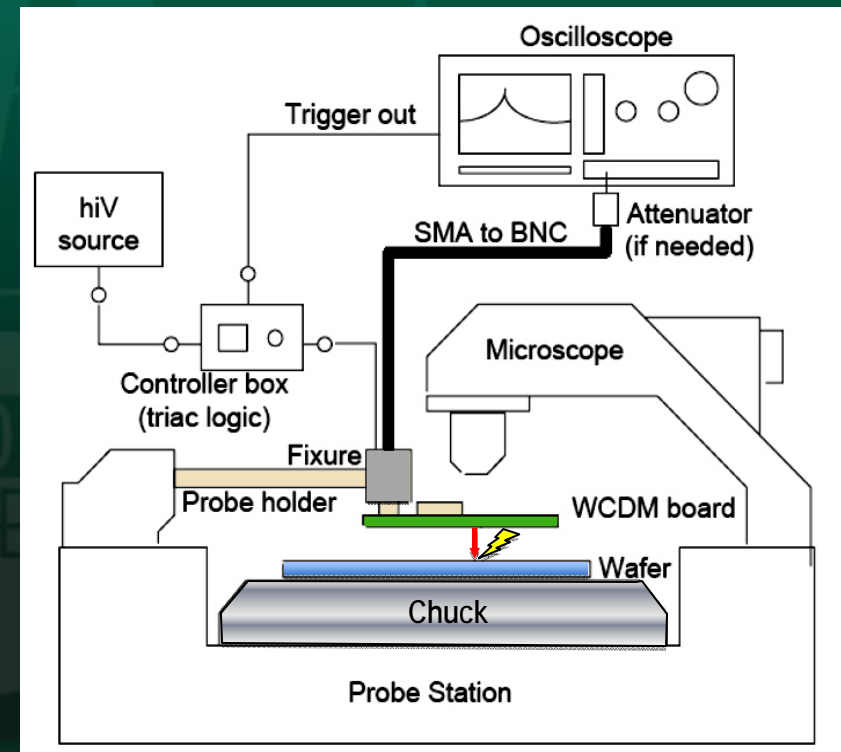


# WCDM (Wafer Charge Device Model)

- Discharge path of metal disk is through a single probe (red)
- CDM spark occurs as disk is lowered to make probe contact

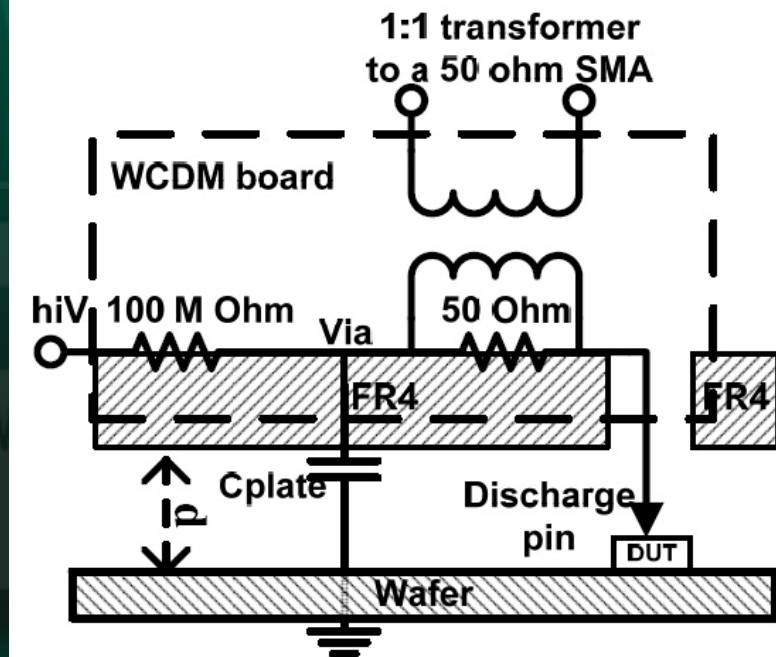
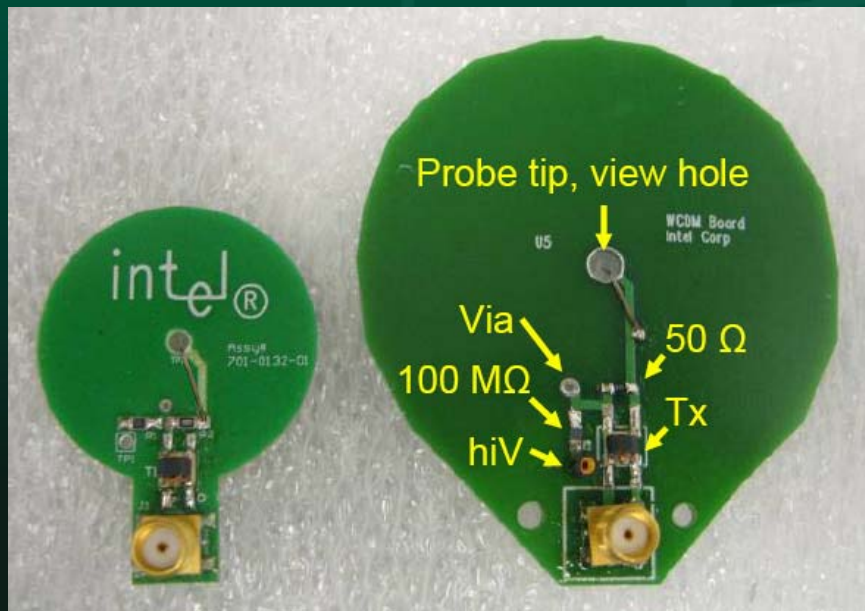


Intel - [12] Chou EOS/ESD 2008



# WCDM (Wafer Charge Device Model)

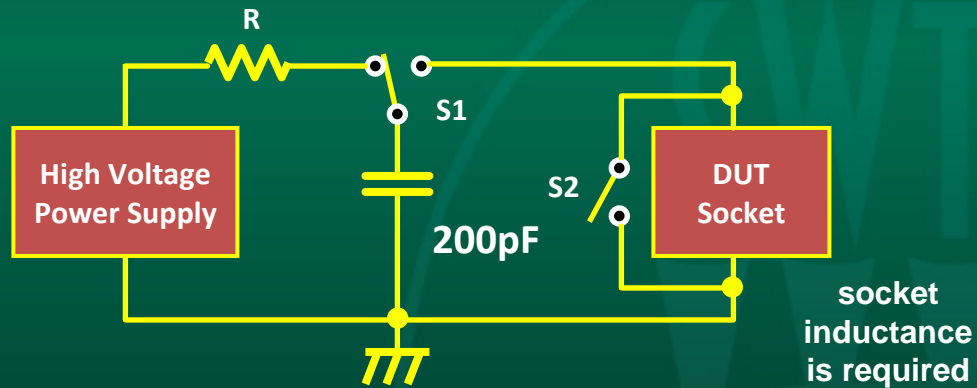
- Two WCDM boards scaled for 5pF and 15pF capacitance
- This simulates small & large package cap. in CDM tests
- Discharge is thru a cantilever tungsten probe tip



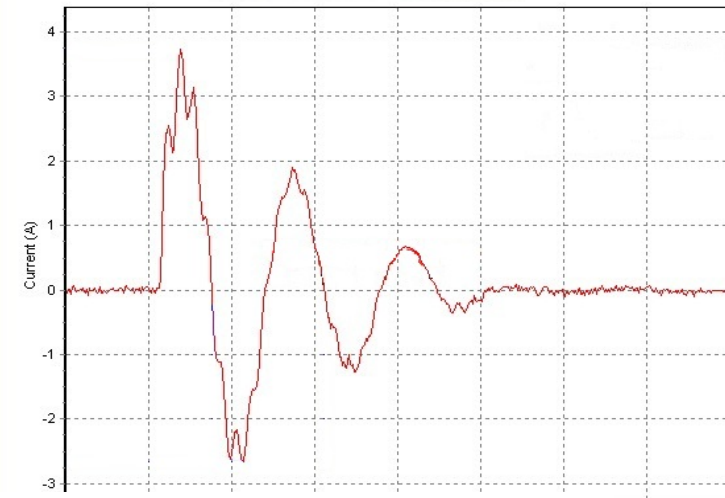
[12] Chou EOS/ESD 2008



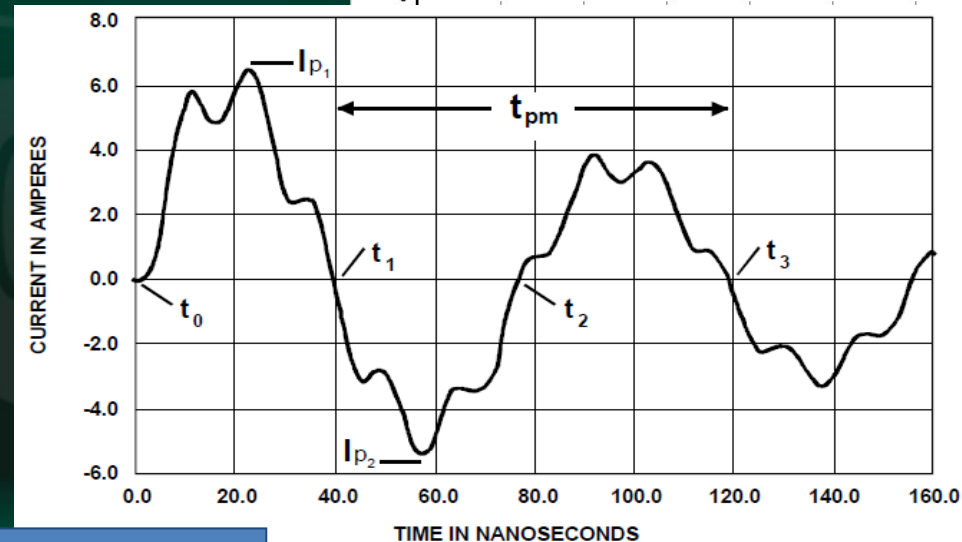
# MM (Machine Model)



MM System Cal. Measurement



- Under-damped sine wave
- Waveform created by parasitic inductance
- Not the best waveform for wafer-level test !

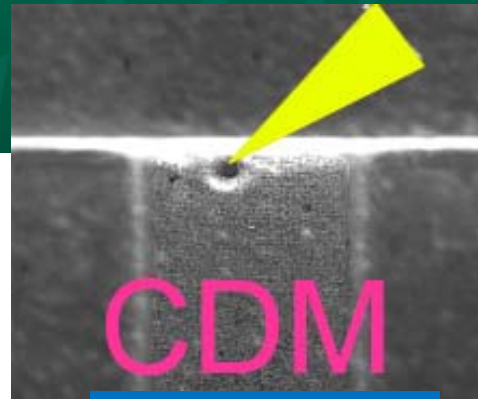
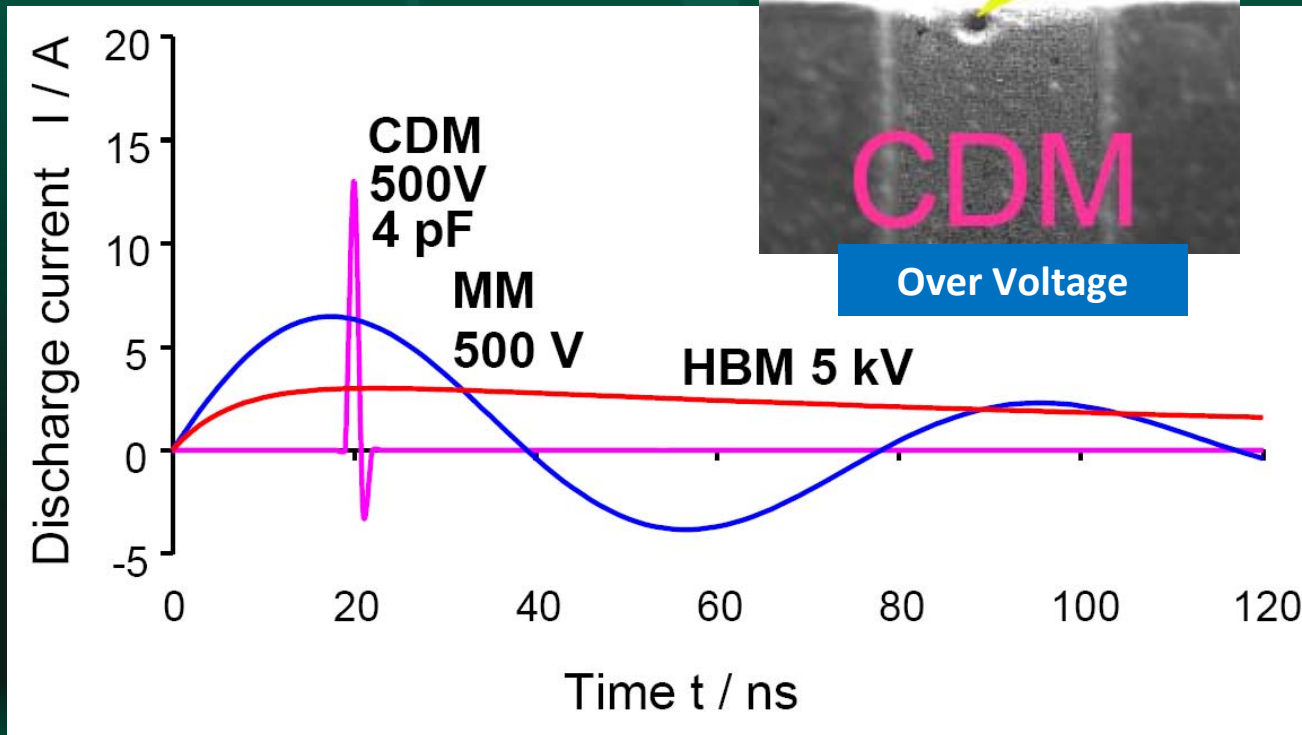


From ESDA STM 5.2

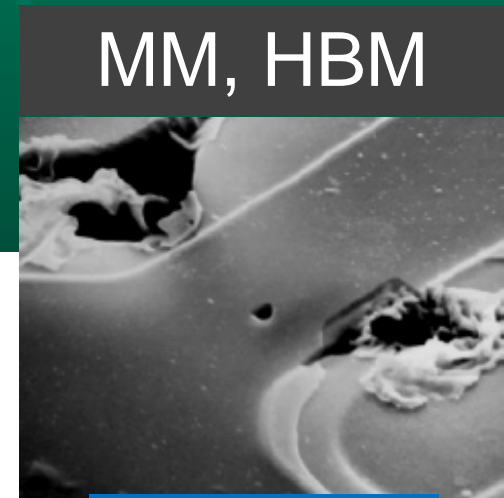


# Comparison – CDM, MM, HBM

- Short pulses produce pin holes and cratering
- Longer pulse waveforms cause melting



Over Voltage

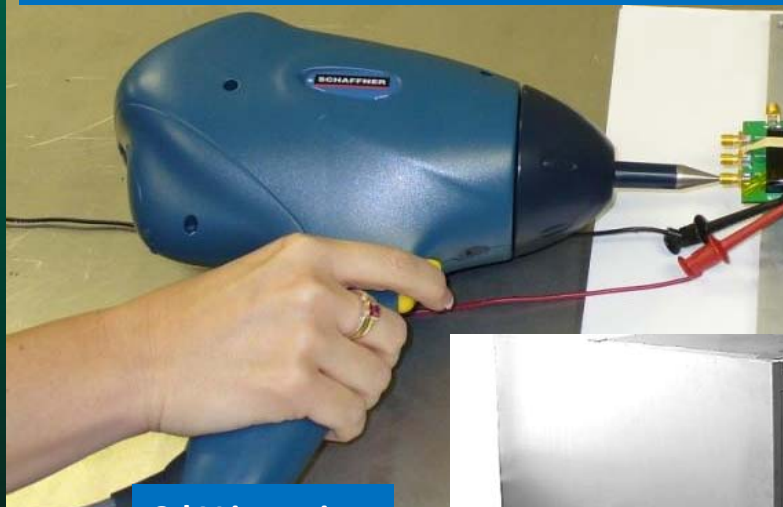


Energy

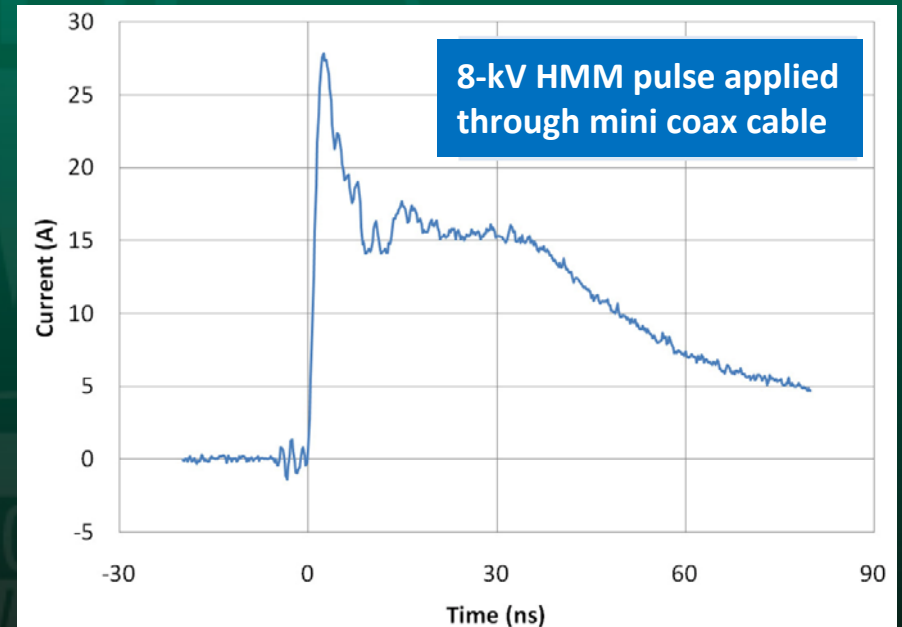
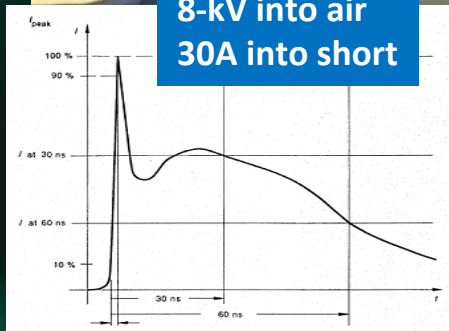
# HMM (Human Metal Model)

- Simulates ESD short & long pulse effects; IEC 61000-4-2
- Use a 50Ω pulse delivery at wafer-level; *Not the Gun!*

Schaffner ESD Simulator Gun (not 50Ω output)



8-kV into air  
30A into short



8 mil OD 50Ω cable passes CE Mark test using 50Ω delivery of IEC 61000-4-2



# ESD-TDB (Time Dependent Breakdown)

- **Toshiba Example (very similar to TDDB)**

- Low voltage CDM investigation

- Dec 2008 – Nozomu Kawai, Nobuyuki Wakai

- < 500V VF-TLP pulse stream on wafer

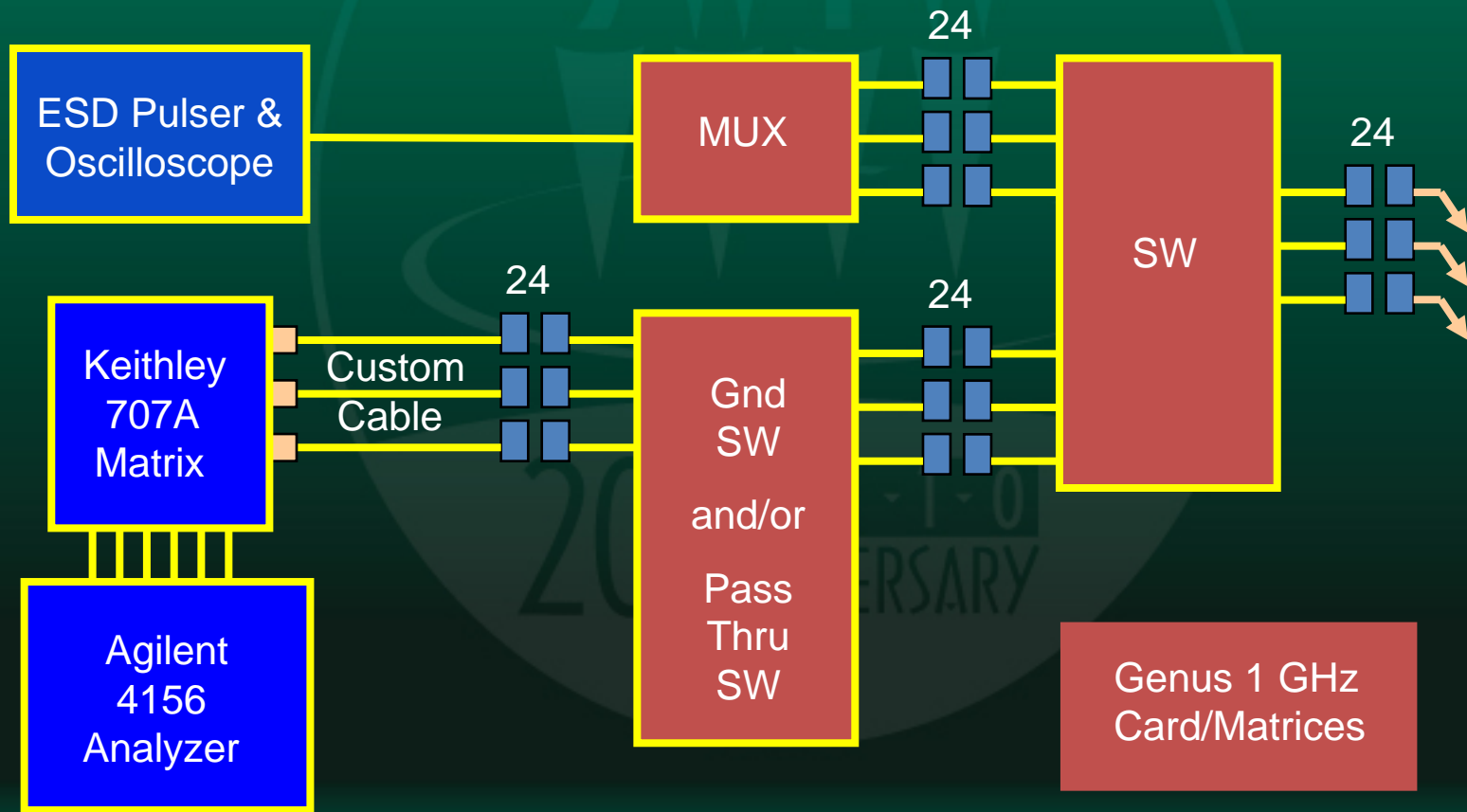
- Monitor leakage degradation (wear out)

- Same test methodology could be applied to standard TLP or HBM pulse streams.



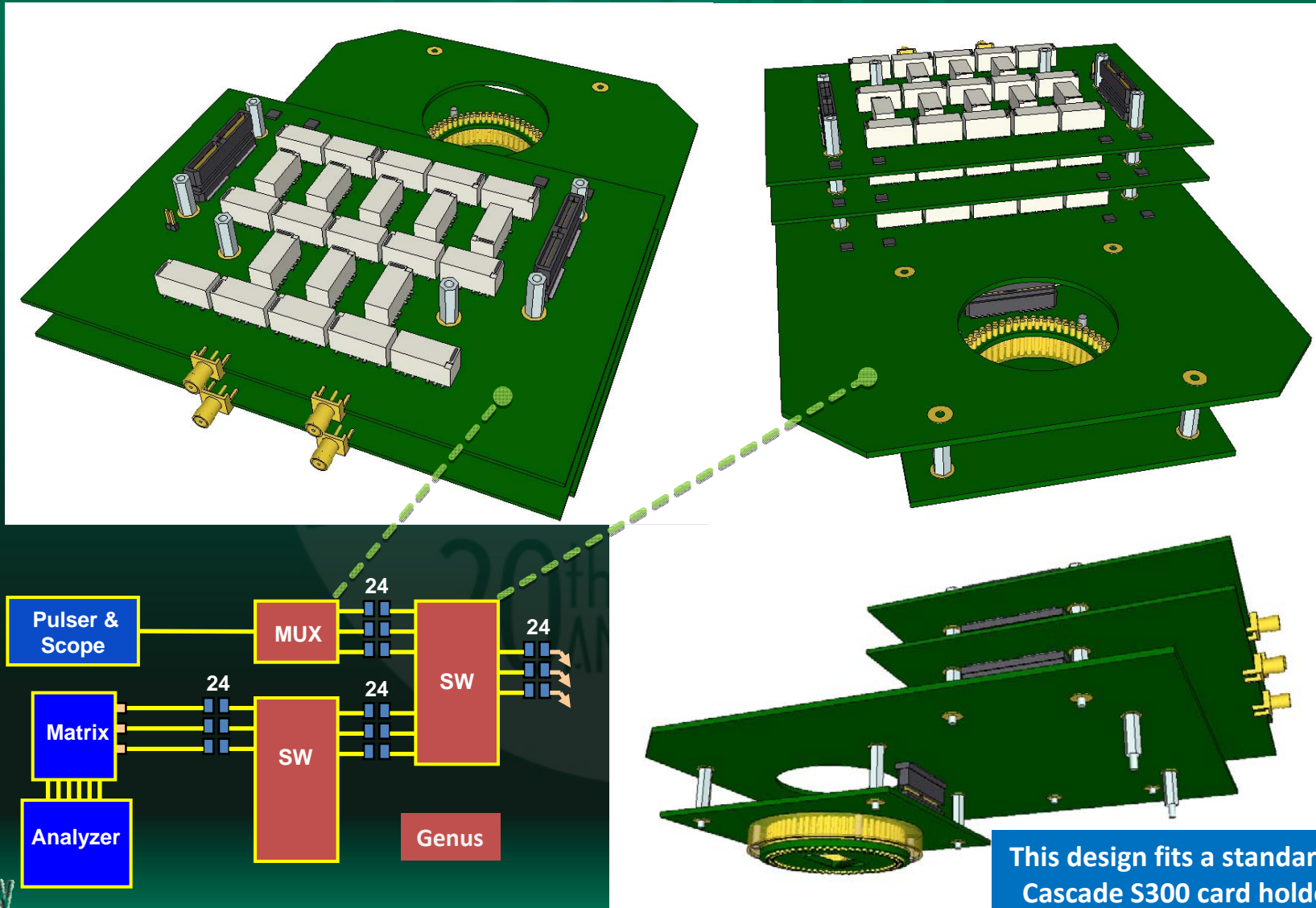
Leakage measured in log time intervals until target %change is reached or device failure

# ESD Pulse Delivery With Full DC Parametric Analysis





# 3-D Views of Genus Probe Card/Matrix



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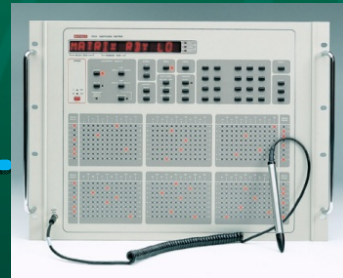
17

# 24 Pin DC + HBM Automation

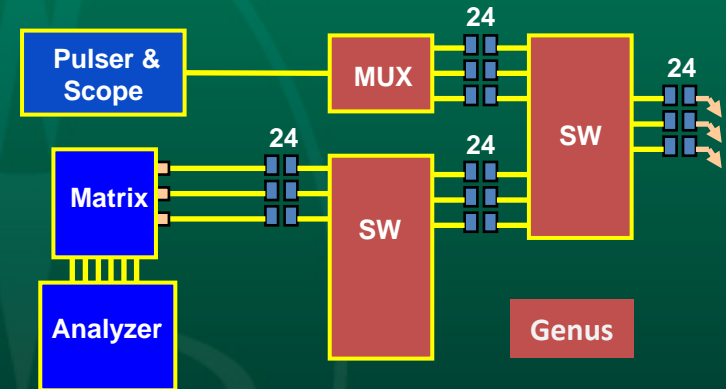
- Precise PIV characterization – data points every 200ps



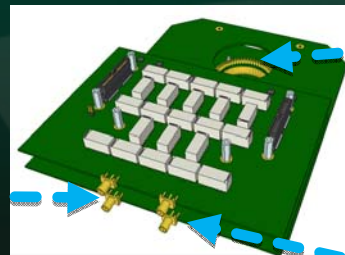
Semiconductor Parameter Analyzer



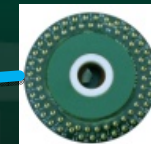
Low Leakage Matrix



Arcus HBM Pulse System

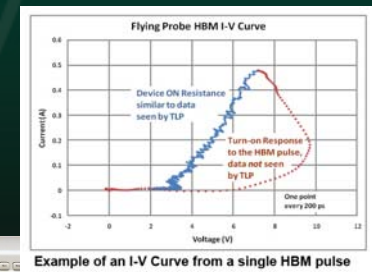


Genus 1 GHz Modular Pin Expander

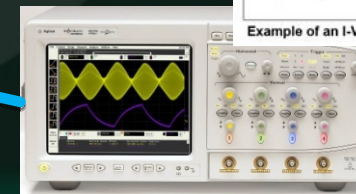


C60 Donut Probe Card

PIV turn-on response to HBM waveform



Example of an I-V Curve from a single HBM pulse



Oscilloscope



# Calibration Is A Big Issue

- **System Corrections**

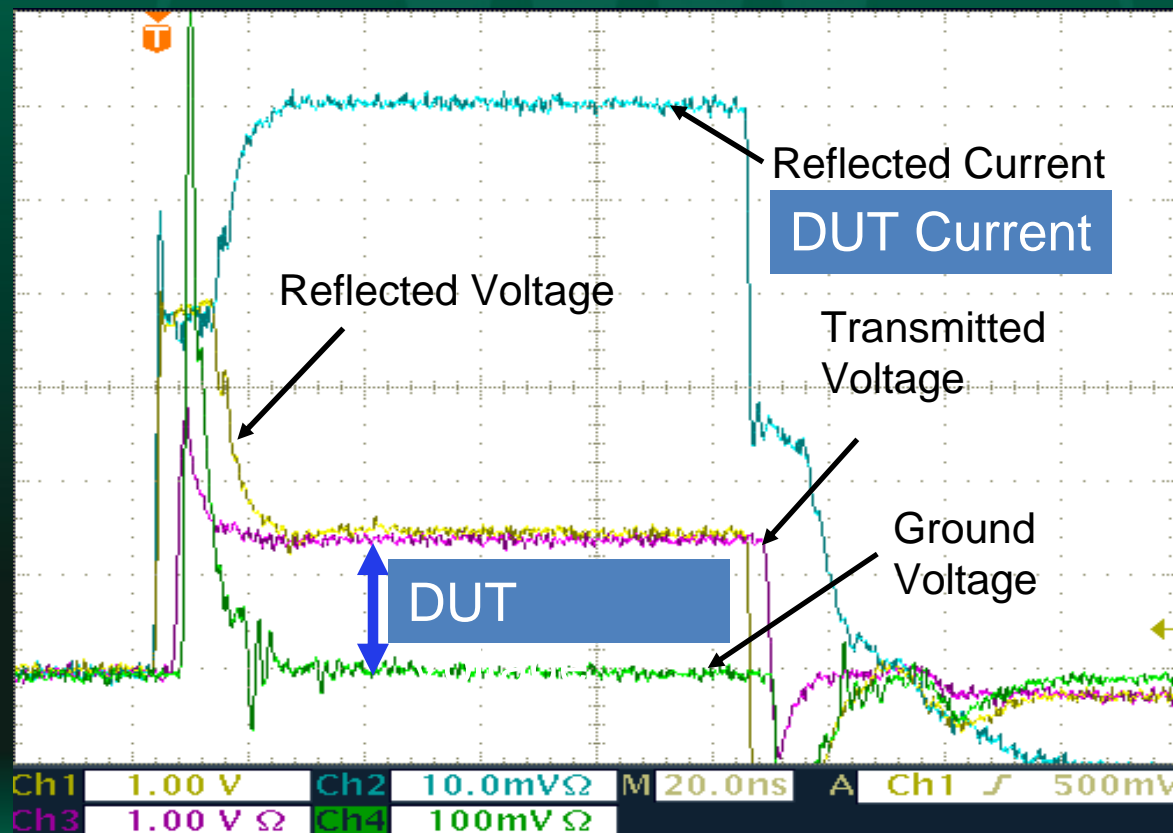
- Open & Short calibration required
- Shorting structure tested at low & high power
- Oscilloscope gain & offset correction
- Inductive current sensor linearity correction
- Multiple pin interaction corrections
- Non-Kelvin correction for contact resistance
- Kelvin correction for sense high impedance attenuation

Each raw data point gathered is process by complex vector math equations to account accurately for all correction factors.



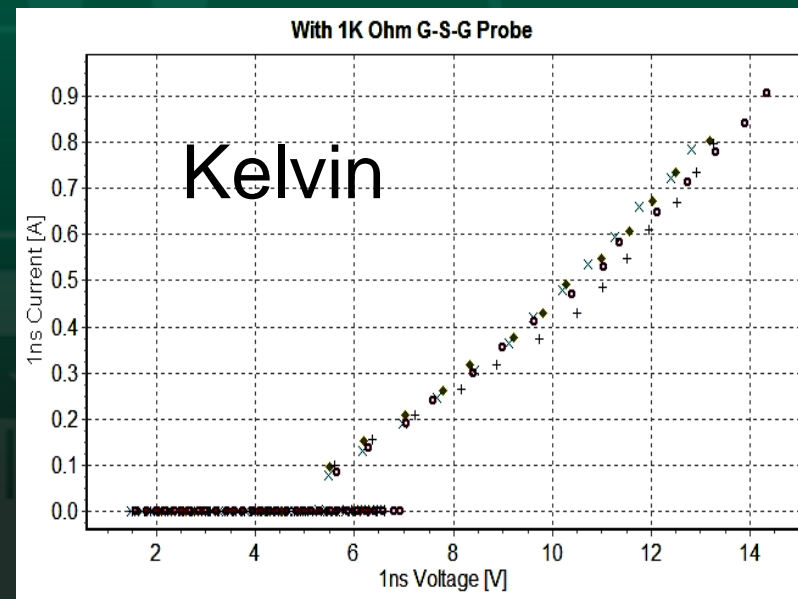
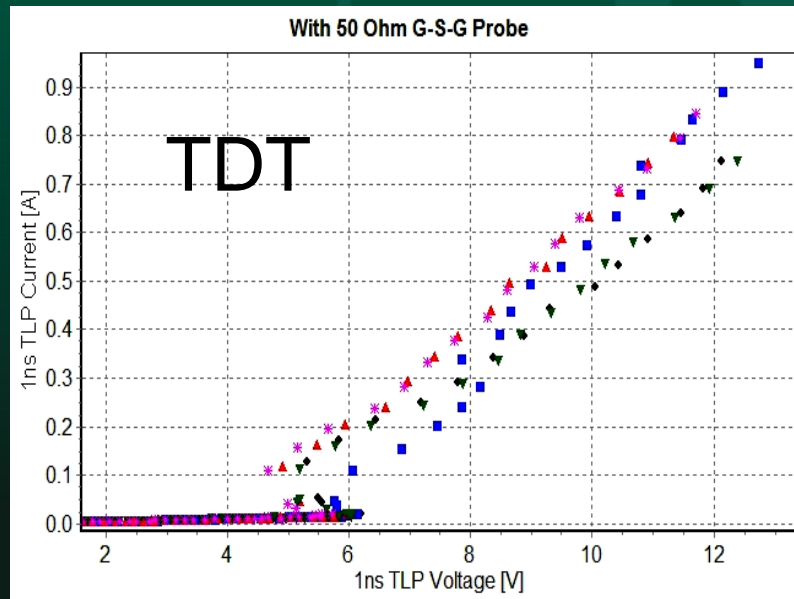
# Kelvin TDR Waveforms

- TLP pulse is delivered with high current force probes
- Separate sense probes measure differential voltage



# Performance of TDT and Kelvin

- Measured with 1.2nS pulses
- Kelvin removes the variation of contact resistances



# Conclusions

- **Automated ESD scribeline test is now a reality**
  - TLP, HBM, HMM, WCDM, Pulse IV Curve Tracing
  - These tests can be combined with traditional parametric test suites for single touch down characterization
- **Challenges to full TEG automation are solvable**
  - WCDM & VFTLP are constrained to one or two pins
  - Most ESD tests can be automated for full parametric TEG testing using the Genus probe card/switch matrices
  - Sophisticated calibration routines maintain accurate measurements at all probe card needles
  - Modular design of matrices adapt to future test needs

